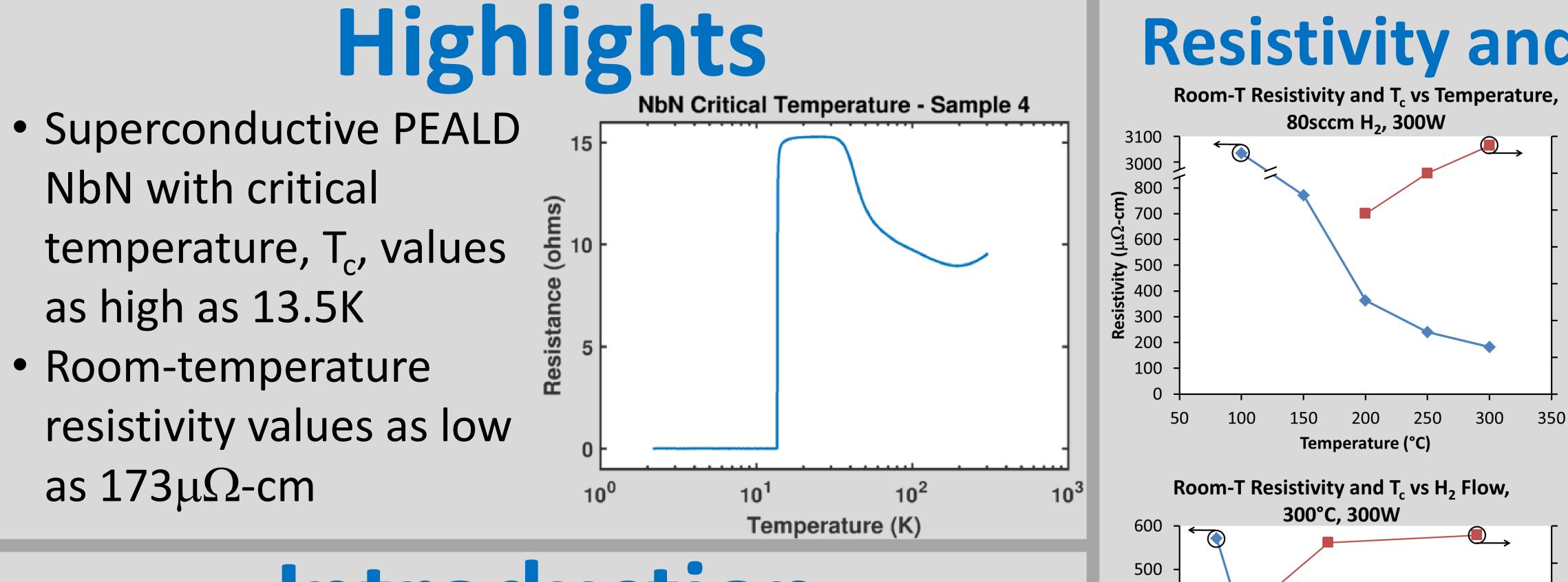
Plasma-Enhanced Atomic Layer Deposition of Superconducting NbN Films Ultratech CNT Mark J. Sowa<sup>a</sup>, Yonas Yemane<sup>b</sup>, Fritz Prinz<sup>b</sup>, J Provine<sup>b</sup> <sup>a.</sup> Ultratech-CNT b. Stanford University



### **Resistivity and Superconductivity**

14

12

10

14

12

Г<sub>с</sub> (К)

• Resistivity decrease and  $T_c$ increase depend primarily on temperature and  $H_2$  flow rate increases

Plasma power increase is a secondary influence on decreasing resistivity and increasing T<sub>c</sub>

Nb-rich films have lower resistivity and higher T<sub>c</sub>
 Negative linear relationship

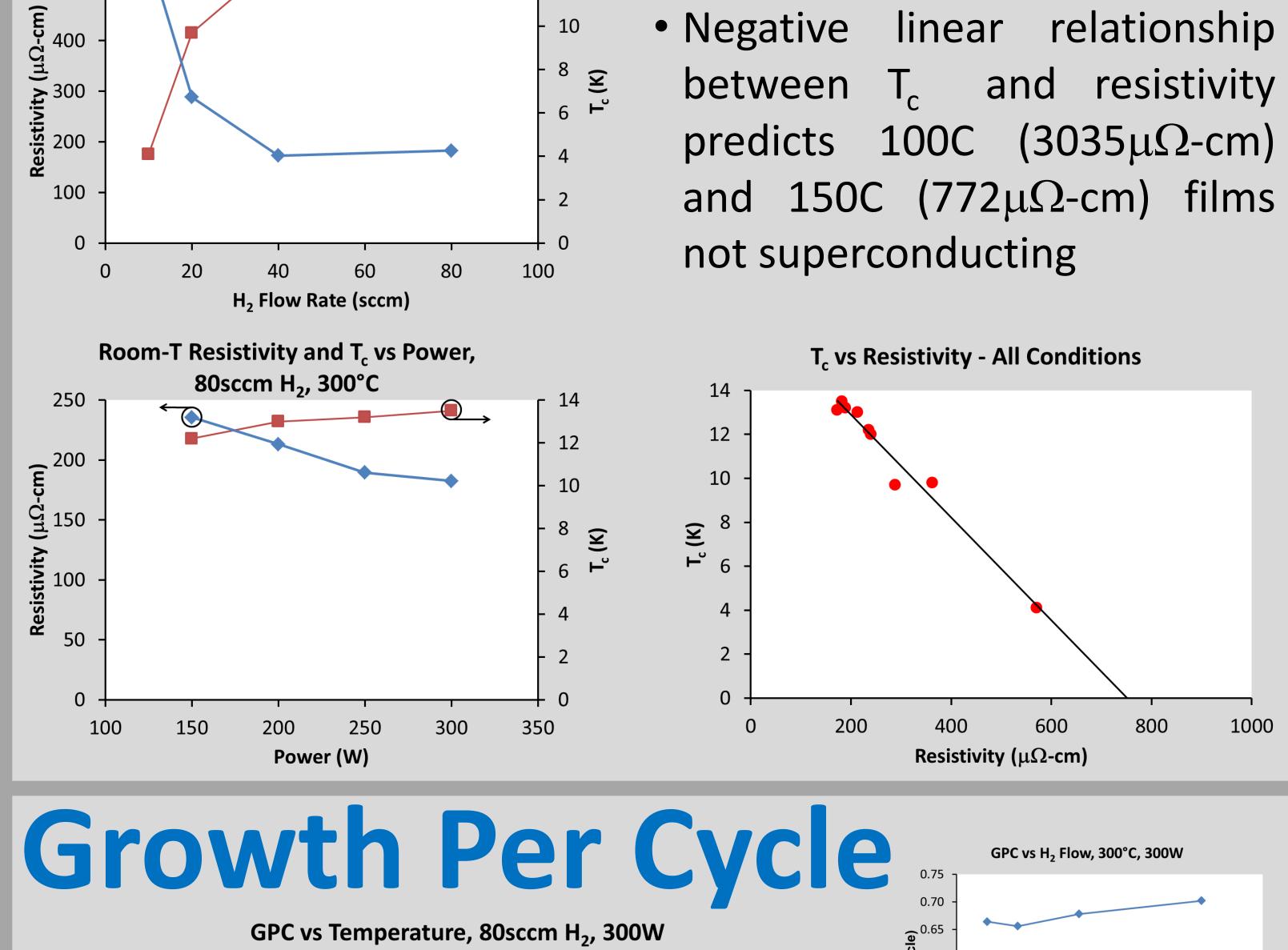
#### 

- NbN is a Type II superconductor with a T<sub>c</sub> of about 16K<sup>1</sup>
- Superconducting NbN has been deposited by Plasma-Enhanced Atomic Layer Deposition (PEALD) previously.<sup>2</sup>
  - $T_c = 10.2K$ , Room T resistivity =  $250\mu\Omega$ -cm
- PEALD NbN has been studied for gate electrode applications:
  - Nb(N-t-Bu)(NMeEt)<sub>3</sub> + H<sub>2</sub> plasma, 715 $\mu\Omega$ -cm<sup>3</sup>
  - Nb(N-t-Bu)(NMeEt)<sub>3</sub><sup>4</sup>
- Improvements in PEALD NbN process may lead to higher T<sub>c</sub> and lower resistivity values

# Experimental

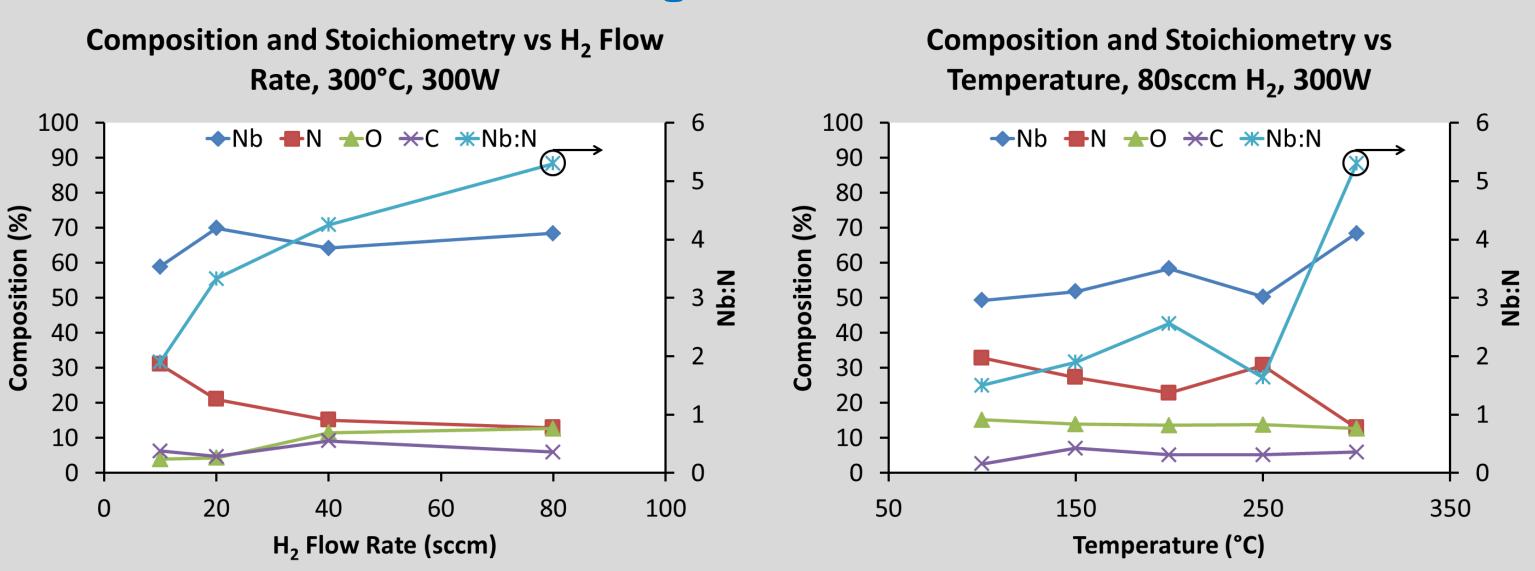
- PEALD of NbN films on an Ultratech/CNT Fiji
- (t-butylimido) tris(diethylamido) niobium(V) (TBTDEN) (100°C)

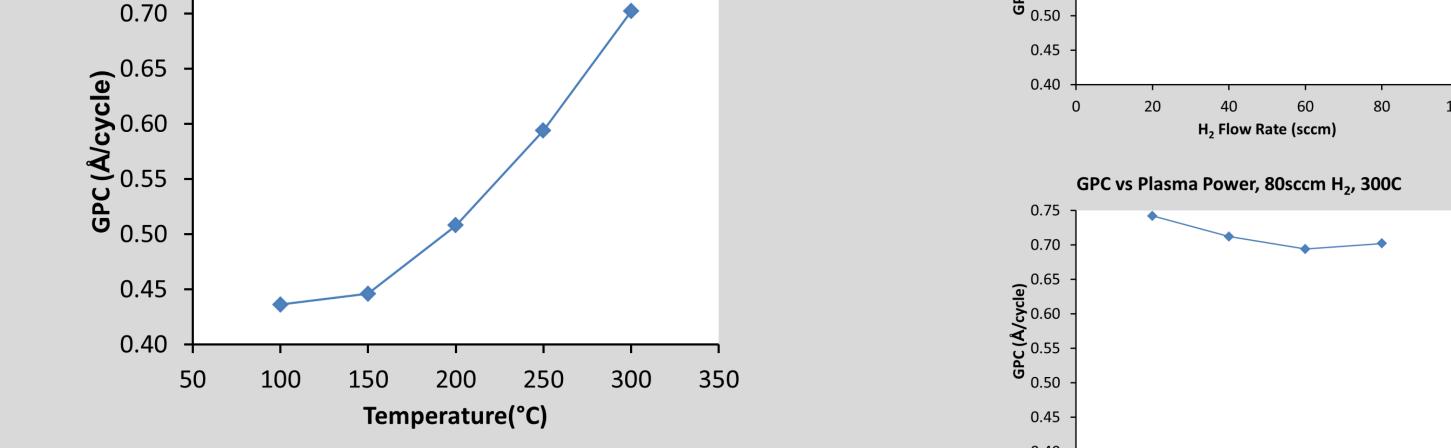
500 cycles	<b>TBTDEN Pulse</b>	<b>TBTDEN Purge</b>	Plasma	Plasma Purge
Carrier Ar (sccm)	30	30	10	30
Plasma Ar (sccm)	100	100	0	100
Plasma H <sub>2</sub> (sccm)	0	0	0—80	0
Plasma N <sub>2</sub> (sccm)	5	5	5	5
Pump Speed	Low	High	High	Low
Power (W)	0	0	150-300	0
Time (sec)	3x Boost <sup>TM</sup>	8	40	5
Temperature (°C)	100 - 300			



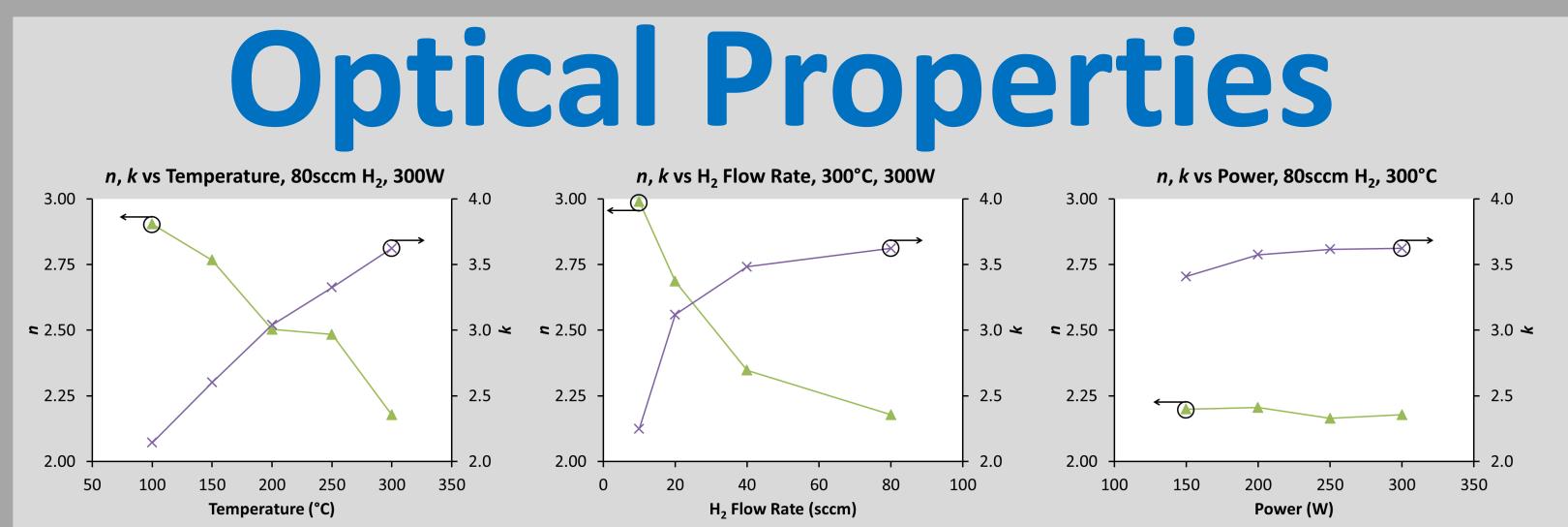
- Spectroscopic ellipsometry for film thickness, *n*, and *k*
- Four point probe technique to assess thin film resistivity
- T<sub>c</sub> measured with Quantum Design PPMS through a Stanford Research Systems SR830 lock-in amplifier
- Composition data from PHI Versaprobe XPS

# Composition





- GPC primarily depends on temperature
  Small GPC increase with H<sub>2</sub> flow at 300°C/300W
- Small GPC decrease over power range at 80sccm H<sub>2</sub>/300°C



- Binding energy of the Nb 3d<sub>5/2</sub> peak is ~203.5 eV for all samples consistent with NbN (203.5 204 eV) or NbO (202.8 204.8 eV) but not Nb metal (201.8 202.5 eV)<sup>5</sup>
- C1s peak at ~282.5 eV suggests presence of NbC<sup>5</sup>
- Depositions resulted in Nb-rich films
- H-rich plasmas deplete film of N resulting in higher Nb:N
- Temperature increase increases Nb and decreases N resulting in higher Nb:N

#### Acknowledgements

• The authors would like to thank Dr. Jinsong Zhang from Prof. Yi Cui's group at Stanford University for helping us with the superconductivity measurements.

- Refractive index decreases and extinction coefficient increases depend primarily on temperature and H<sub>2</sub> flow rate increases
  Plasma power increase is a secondary influence on decreasing n
  - and increasing k
- Higher k and lower n in Nb-rich films



- Superconductive PEALD NbN with  $T_c$  values as high as 13.5K
- Room-temperature resistivity values as low as 173µΩ-cm
  Resistivity and *n* decrease, T<sub>c</sub> and *k* increase as NbN films become more Nb-rich at high deposition temperature, high H<sub>2</sub> flow rate, and high plasma power.
- 1. B. T. Matthias, et al., Rev. Mod. Phys. 35, 1 (1963).

0.75

- 2. M. Ziegler, et al., Supercond. Sci. Technol. 26 (2013) 025008.
- 3. J. Hinz, et al., Semicond. Sci. Technol., Volume 25, 075009, 2010.
- 4. J. Hinz, et al., Semicond. Sci. Technol., Volume 25, 045009, 2010.
- 5. J. F. Moulder, *Handbook of X-ray Photoelectron Spectroscopy*, edited by J. Chastain (Perkin-Elmer Corporation, 1992).